

98-2 Preliminary Syllabus, Da-Yeh Univ

Information			
Title	真空與薄膜應用	Serial No. / ID	2732 / EGR5264
Dept.	電機工程學系碩士班	School System / Class	研究所碩士班1年1班
Lecturer	宋皇輝	Full or Part-time	專任
Required / Credit	Optinal / 3	Graduate Class	NO
Time / Place	(二)6 / H341 (四)56 / H341	Language	Chinese

Introduction
<p>The purpose of this course is to enable students with the basic concept of the vacuum system, know how to create a show together in the vacuum deposited thin film systems, understanding the advantages and disadvantages of various thin film deposition methods, and introduces the film properties, measurement and analysis methods, and the film made Micro-nano-scale patterns of related technologies.</p>

Outline
<ol style="list-style-type: none"> 1.Introduction 2.Vacuum Technology 3.Gas Properties. 4.Vacuum Gauges and Flow Meters. 5.Partial Pressure Analysis. 6.Vacuum Pumps. 7.Materials in Vacuum. 8.Leak Detection and Leak Detectors. 9.High-Vacuum System Design. 10.Thin Films Deposition 11.Physical Vapor Deposition. 12.Chemical Vapor Deposition. 13.Thin Films Characterization 14.Electrical and Electronic Properties 15.Optical Properties 16.Lithography and Pattern Transfer.

Prerequisite
General Physics